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Docket No. 1232-4421US1

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**Applicant(s) :** UEHARA et al.

**Serial No. :** 09/664,715                   **Art Unit :** 1765

**Filed :** September 19, 2000                   **Examiner :** K. Chen

**For :** WAFER PROCESSING APPARATUS, WAFER PROCESSING METHOD, AND SEMICONDUCTOR SUBSTRATE FABRICATION METHOD

**REQUEST FOR ACKNOWLEDGEMENT OF  
CLAIM TO CONVENTION PRIORITY**

**MAIL STOP –** \_\_\_\_\_  
**COMMISSIONER FOR PATENTS**  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicants hereby request that the Examiner acknowledge Applicants' 35 U.S.C. 119(a) claim to foreign priority in the instant application, which is a divisional of application Serial No. 09/025,409, filed February 18, 1998 (parent '409 application). Certified copies of the earlier Japanese applications. i.e., JP 9-038079 and JP 9-038080, both filed February 21, 1997, were filed in the parent '409 application on April 28, 1998 and acknowledgment of receipt was made during prosecution thereof. The Office Action mailed August 4, 2003 did not include any acknowledgement of Applicants' claim for priority under 35 U.S.C. 119(a) and that certified copies of the subject Japanese applications were received in the parent '409 application.

For the convenience of the Examiner, a copies of the (1) Claim To Convention Priority, (2) copies of the first page of the certified copy of JP 9-038079, filed February 21, 1997, and an English translation thereof, (3) copies of the first page of the certified copy of JP 9-038080, filed February 21, 1997, and (4) a copy of the itemized post card receipt date stamped by the United States Patent and Trademark Office on "APR 28, 1998."

Request for Acknowledgement of Claim to Convention Priority

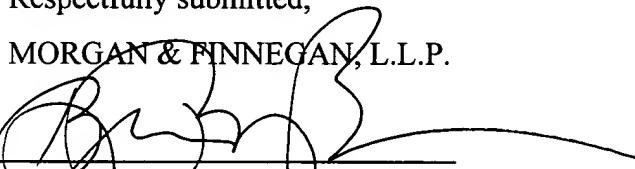
No fee is believed to be required for the filing of this Request. The Commissioner, however, is hereby authorized to charge any additional fees, which may be required for the timely consideration of this Request, or credit any overpayment, to Deposit Account No. 13-4500, Order No. 1232-4421US1.

Respectfully submitted,

MORGAN & FINNEGAN, L.L.P.

Dated: November 20, 2003

By:



Brian W. Brown, Reg. No. 47,265  
(202) 857-7887 Telephone  
(202) 857-7929 Facsimile

**Correspondence Address:**

MORGAN & FINNEGAN, L.L.P.,  
345 Park Avenue  
New York, New York 10154



Our Ref: 1232-4421

Application Serial No.: 09/025,409

Date Due \_\_\_\_\_

Atty MAS/tmp

Date This Paper is being Filed April 28, 1998

Entitled: **WAFER PROCESSING APPARATUS, WAFER PROCESSING  
METHOD, AND SEMICONDUCTOR SUBSTRATE FABRICATION  
METHOD**

The return of this post card, properly stamped, will acknowledge receipt  
in the Patent & Trademark Office of the following:

1. Claim to Convention Priority (in duplicate).
2. Priority Document 9-038079, 9-038080



Our Ref: 1232-4421

Application Serial No.: 09/025,409

Date Due \_\_\_\_\_

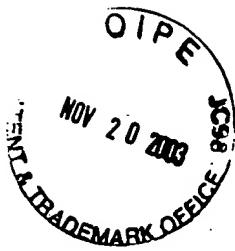
Atty MAS/tmp

Date This Paper is being Filed April 28, 1998

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1. Claim to Convention Priority (in duplicate).
2. Priority Document 9-038079, 9-038080



PATENT

Docket No. 1232-4421

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Fumio UEHARA, et al.

Group Art Unit: Unknown

Serial No. : 09/025,409

Examiner: Unknown

Filed : February 18, 1998

For : WAFER PROCESSING APPARATUS, WAFER PROCESSING METHOD,  
: AND SEMICONDUCTOR SUBSTRATE FABRICATION METHOD

CLAIM TO CONVENTION PRIORITY

ASSISTANT COMMISSIONER FOR PATENTS  
Washington, D.C. 20231

Sir:

In the matter of the above-identified application and under the provisions of 35 U.S.C. § 119 and 37 C.F.R. § 1.55 applicant(s) claims(s) the benefit of the following prior applications:

Application filed in :	JAPAN	JAPAN
In the name of :	CANON	CANON
Serial No. :	9-038079	9-038080
Filing Date :	February 21, 1997	February 21, 1997

1.  Pursuant to the Claim to Priority, applicant(s) submit(s) a duly certified copy of said foreign application.

2. [ ] A duly certified copy of said foreign application is in the file of application Serial No. \_\_\_\_\_, filed \_\_\_\_\_.

Respectfully submitted,

MORGAN & FINNEGAN, L.L.P.

*Michael A. Schwartz*

By:

Michael A. Schwartz  
Registration No. 40,161  
(202) 857-7887 Telephone  
(202) 857-7929 Facsimile

Dated: April 28, 1998

CORRESPONDENCE ADDRESS:

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FORMS: AMD-TRAN.NY  
Rev. 11/13/97

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PATENT OFFICE  
JAPANESE GOVERNMENT

別紙添付の書類に記載されている事項は下記の出願書類に記載されて  
る事項と同一であることを証明する。

This is to certify that the annexed is a true copy of the following application as filed  
this Office.

願年月日  
Date of Application:

1997年 2月21日

願番号  
Application Number:

平成 9年特許願第038080号

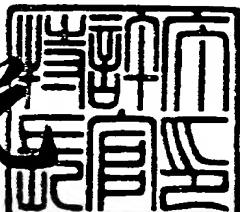
願人  
Applicant(s):

株式会社丸和製作所  
キヤノン株式会社

1998年 3月20日

特許庁長官  
Commissioner,  
Patent Office

荒井寿光



出証番号 出証特平10-3016721

(Translation of the front page  
of the priority document of  
Japanese Patent Application  
No. 9-038080)

PATENT OFFICE  
JAPANESE GOVERNMENT

This is to certify that the annexed is a true copy of  
the following application as filed with this Office.

Date of Application : February 21, 1997

Application Number : Patent Application

9-038080

Applicant(s) : KABUSHIKI KAISHA MARUWA SEISAKUSHO  
CANON KABUSHIKI KAISHA

March 20, 1998

Commissioner,

Patent Office

Hisamitsu ARAI

Certification Number 10-3016721

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SG TH TW

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PATENT OFFICE  
JAPANESE GOVERNMENT

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事項と同一であることを証明する。

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in this Office.

願年月日  
of Application: 1997年 2月 21日

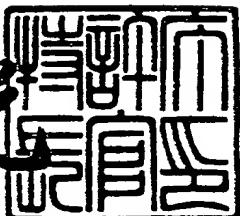
願番号  
Application Number: 平成 9年特許願第038079号

願人  
Applicant(s): 株式会社丸和製作所  
キヤノン株式会社

1998年 3月 20日

特許庁長官  
Commissioner,  
Patent Office

荒井寿光



出証番号 出証特平10-3016713

(Translation of the front page  
of the priority document of  
Japanese Patent Application  
No. 9-038079)

PATENT OFFICE  
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This is to certify that the annexed is a true copy of  
the following application as filed with this Office.

Date of Application : February 21, 1997

Application Number : Patent Application

9-038079

Applicant(s) : KABUSHIKI KAISHA MARUWA SEISAKUSHO  
CANON KABUSHIKI KAISHA

March 20, 1998

Commissioner,

Patent Office Hisamitsu ARAI

Certification Number 10-3016713